

LAM Research
4420 Oxide Etch 125mm Configuration
SN 3195

LAM Research 4420 Oxide Etch SN 3195 Location warehouse Nijmegen condition As -Is



Tool Model: 4420

Current Tool Serial Number: 3195

Bulkhead system mount w/tunnel covers

Hine 38A open cassette Send/Receive indexers

Software Version: Envision

Oxide etcher, 5" 4,6 and 8 inch optional

Clamp type/ ESC optional Onboard AE RF generator

Moving gap

Back Helium Colling

Main Power 208V, 3 Phase, 5Wire, 175A, 60/

Belt driven load station

Standard load station shuttle spatula Upper chamber gap drive encoder Aluminum upper chamber electrode Single lower chamber endpoint detector (405/520nm) Non-

Low pressure chamber manifold HPS valve for chamber isolation AC--2 chamber pressure control

Lower chamber RGA port

Millipore CMHT--11S02 10 Torr chamber manometer

Millipore CMLA--21 100 Torr backside helium manometer

Tylan General CMHT--11S02 10 Torr reference manometer

8 -- Gas box Orbital gas box

Gas 1: To custemer Spec

Gas 2: To custemer Spec

Gas 3: To custemer Spec

Gas 4: To custemer Spec

Gas 5: To custemer Spec

Gas 6: To custemer Spec

Gas 7: To custemer Spec

Gas 8: To custemer Spec

UPC: He (50 sccm) -- Unit 1300 Trip breakers AC/DC power box

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